

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re U.S. Patent Application of)
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HATANO et al.)
)
Application Number: To be Assigned)
)
Filed: Concurrently Herewith)
)
For: METHOD FOR FABRICATING IMAGE DISPLAY)
DEVICE)
)
ATTORNEY DOCKET NO. HITA.0407)

**Honorable Assistant Commissioner
for Patents
Washington, D.C. 20231**

INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §§ 1.56 and 1.97, this Information Disclosure Statement is submitted in the above-identified patent application. A listing of documents to be published on the face of any patent granted from this application is submitted herewith on Form PTO-1449.

Any other documents or information submitted for consideration by the Examiner are listed in this paper. A copy of each U.S. and foreign patent, or each publication or portion thereof listed or herein identified, is submitted herewith.

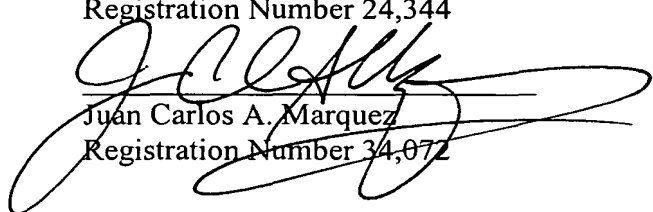
This Information Disclosure Statement is submitted with the initial filing of the application. Accordingly, no fee is due or payable at this time.

The Examiner is requested to acknowledge consideration of the information provided in this paper in accordance with prescribed procedures.

Please charge any additional fees or credit any overpayments in connection with this paper to Deposit Account No. 08-1480.

Respectfully submitted,

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Form PTO 1449 U.S. Department of Commerce Patent and Trademark Office Information Disclosure Statement by Applicant	ATTY. DOCKET NUMBER HITA.0407	SERIAL NUMBER To be Assigned
	APPLICANT HATANO et al.	
	FILING DATE Concurrently Herewith	GROUP

U.S. Patent Documents

Examiner Initial		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE

Foreign Patent Documents

Examiner Initial		DOCUMENT NUMBER	FILING DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
							YES	NO
		2002-43222	2/21/95	Japan			Abstract	X
		2002-100637	2/21/95	Japan			Abstract	X

Other Documents (Including Author, Title, Date Pertinent Pages, Etc.)

		C.T. Angelis, C.A. Dimitriadis, M. Miyasaka, F.V. Farmakis, G. Kamarinos, J. Brini and J. Stoemenos, "Effect of Excimer Laser Annealing on the Structural and Electrical Properties of Polycrystalline Silicon Thin-Film Transistors", Journal of Applied Physics (15 October 1999), Vol. 86, No. 8, pp. 4600-4606
		Hiroyuki Kuriyama, Tomoyuki, Nohda, Satoshi Ishida, Takashi Kuwahara, Shigeru Noguchi, Seiichi Kiyama, Shinya Tsuda and Shoichi Nakano, "Lateral Grain Growth of Poly-Si Films with a Specific Orientation by an Excimer Laser Annealing Method", Jpn. J. Appl. Phys., Vol. 32 (1993), pp. 6190-6195
		Kenkichi Suzuki, Masakazu Saitou, Michiko Takahashi, Nobuaki Hayashi and Takao Terabayashi, "Correlation Between Power Density Fluctuation and Grain Size Distribution of Laser Annealed Poly-Crystalline Silicon", Part of the SPIE Conference on Laser Applications in Microelectronics and Optoelectronic Manufacturing IV, January 1999, SPIE Vol. 3618, pp. 310-319

EXAMINER	DATE CONSIDERED
<i>EXAMINER: Initial if citation is considered, whether or not citation is in conformance with MPEP 609; draw a line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant</i>	